

Section 8. Complex Systems

- 8.1 Cubic-200 MBE System
- 8.2 Medium Size MBE System
- 8.3 Full Size MBE System
- 8.4 Radial Distribution Sample Transfer System



Fe Se Mn Cu Ge Ag In Sb Ba Au Te Pb Bi Sm ...

Cubic-200 MBE System



Highlights

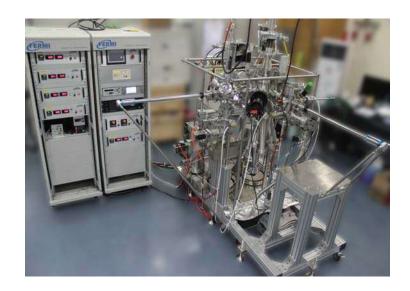
- Chamber is made from one piece of SS316
- No welding part, guarantees the lowest possibility of leaking
- DN100CF, x 6DN40CF flanges, x 8
- 300L/s Turbo Pump and oil-free scroll pump
- QCM (Inficon or K.J. Lesker) with linear shift
- Wide range gauge (or lon gauge)
- 4-axis manipulator with temperature controller

Specification	Basic	Upgrade Option
Chamber	Made from one piece of SS316	Ti Alloy available
Flanges	DN40CF: 8; DN100CF: 6;	DN40CF: 8; DN100CF: 4; DN150CF: 2;
Turbo Pump	Pfeiffer HiPace 300	Edwards STP301 Mag-Lev TMP
Forevacuum Pump	Edwards nXDS6i	Edwards nXDS10i
Base Pressure	<5E-10 mbar	<5E-10 mbar (or additional Ion Pump/NEG/TSP, base pressure up to 5E-11 mbar)
4-axis Manipulator	X/Y(±8mm), Z(75mm), θ (±180°)	
Temperature Range	RT~1200K	Liquid Nitrogen Cooling Module; E-beam Heating Module
QCM	INFICON STM-2 100mm Linear Shift	INFICON XTC/3s 100mm Linear Shift
Evaporator	Evaporator: 2 sets $ \begin{array}{l} \text{Temperature Range}: 80\text{-}1500^{\circ}\!$	Up to 7 Evaporators Temperature Range : up to 2000℃ Pneumatic Shtters with Controller & Software
Gate Valve	HTC DN63CF Manual Gate Valve	VAT DN63CF Manual Gate Valve
Other Accessories	Load Lock, Sample Transfer, High Stability Chiller	



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Medium Size MBE System



- SS316 UHV Chamber, NW CF Standard
- Base Pressure better than 5.0x10⁻¹⁰mbar
 Improvable with optional Pumps
- Up to 12 ports for evaporators, compatible with all commerial products.
- 4-axis manipulator support flag type sample holder, resistance/e-beam/dc heating, LN2/ He cooling, 4 Probe options.
- Extension Flange Available for In-Situ Characterizat

	Specification	
Chamber	Made from SS316 , fully UHV compatible	
Pumps	Standard: Edwards STP 603 Mag- Lev Turbo Pump with nXDS 10i Dry Pump Optional: TSP, LN2 Trap, Ion Pump, NEG Pump, 2nd stage Turbo Pump	
Base Pressure	<5E-10 mbar (Standard)	
4-axis Manipulator	X/Y(± 8 mm), Z(150mm), θ (+/-180°) , Heating /Cooling on request	
QCM	Retractable INFICON XTC/3s controller and Front Load Single Sensor	
RHEED	STAIB 15 KeV RHEED & Phosphor Screen; CCD & Software for Data acquisition and analysis	
Evaporator Cells	Up to 12 Evaporators: 4 x CF 40 Ports @ 18 degrees 4 x CF 63 Ports @ 20 degrees 4 x CF 40 Ports @ 55 degrees Pneumatic Shtters with Controller Box & Recipe Software	
Gate Valve	VAT DN63 CF UHV Manual Gate Valve	
Other Accessories	Load Lock, UFO Chamber , Ion source, LEED Chamber ARPES/XPS/STM Connections	



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Full Size MBE System







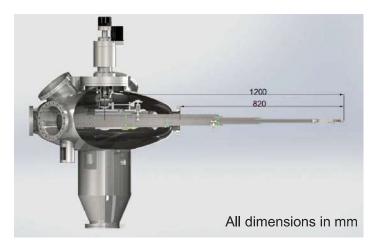
	Specification	
Chamber	Made from SS316 with UHV standard	
Pumps	Edwards STP1003 Mag-Lev Turbo Pump, EXT75DX turbo pump as the second stage backing pump and differential pumping, nXDS10i as the forevacuum pump;	
	TSP with Liquid Nitrogen Cooling Shroud	
Base Pressure	<1E-10 mbar after 48 hours bakeout at 150 $^\circ\mathrm{C}$	
4-axis Manipulator	X/Y(±8mm), Z(150mm), θ (+/-180°)	
	Temperature Range: Liquid Nitrogen Cooling Module, 150~1200K	
QCM	INFICON XTC/3s with 150mm Linear Shift	
RHEED	STAIB 15 KeV RHEED & Phosphor Screen; Data acquisition and Analysis.	
High Purity Ozone System	High purity Ozone source, up to 90% purity; capable to oxidize most material at 1E-6 mbar Ozone atmosphere; Max 16 g/hour Ozone generation capability and storage of 8g liquid Ozone (supporting up to 8 hours of growth process).	
Evaporator Cells	Up to 16 Evaporators Temperature Range : up to 2000°C (with K-cells) up to 3000°C (with E-beam Evaporator) Temperature Stability : ±0.1°C Flange : DN40CF / DN63CF Pneumatic Shtters with Controller & Software	
Gate Valve	VAT DN63/40CF UHV Manual Gate Valve	
Other Accessories	Load Lock, RDC, High Stability Chiller	



Radial Distribution Sample Transfer System

Highlights:

- The sample transfer mechanism and sample transfer chamber has been approved by the China Patent No.: 201520801219.1
- Base pressure: 10⁻¹¹ mbar
- Optimized mechanical structure and materials guarantee less degassing
- Extension capability: up to 8 sub-systems;
- Stroke: 820mm (measured from the port edge), the longest one in the market;
- Motorization upgradable





Chamber Size	700mm Diameter
Mounting Flange of Arm	CF200
Maintenance Flange	CF150
Connecting Flange	CF100
Rotation of Transfer Arm	360 degree continuous
Extending Stroke	820mm
Maximum arm length	1200mm
Rotation accuracy	<0.1 degrees
Highest baking temperature	150°C
Maximum load	1 kg

This Radial Distribution Sample Transfer System is hosted in a UFO shaped chamber and thus normally mentioned as UFO system. The chamber is in UHV standard and made from SS316. UFO Chamber is very important in multi-purpose system as it will connect different systems as one piece and samples can travel freely in UHV environment and could be measured in-situ. Up to 8 sub-systems could be connected to the UFO system. This UFO Assembly is equipped with cutting-edge transfer mechanism and the transfer arm could extend longer than the diameter of the chamber (820 mm from the port edge). This extension is useful and thus sub-systems could sit further away from the UFO and leave more space for operation and system expansion.

